

IN THE CLAIMS:

1. *(amended)* An arrangement for controlling the alignment direction of a light beam comprising:

an active light source for emitting a beam of light;

a passive receiver of light;

a MEMS mirror for receiving said beam of light from said active source and for reflecting said beam of light toward said passive receiver of light wherein said MEMS mirror is electrically controlled to change its deflection profile until alignment is achieved between the active light source and the passive receiver of light;

a monitoring photodiode; and

a beam splitter associated with the MEMS mirror to enable said MEMS mirror to split the beam emitted from said active light source into a first beam and a second beam wherein said first beam is directed toward the passive receiver of light and said second beam is directed toward said monitoring photodiode, wherein a power measurement of said second beam is converted to an electrical signal by the monitoring photodiode and used to electrically change the deflection profile of said MEMS mirror.

2. *cancelled.*

3. *(currently amended)* The arrangement as defined in claim 1 wherein the beam splitter forms the first and second light beams to comprise a predetermined power ratio.

4. *(currently amended)* The arrangement as defined in claim 1 wherein the monitoring photodiode is operably connected to the active light source and to the MEMS mirror whereby a change in the strength of the first and second light beams causes the monitoring photodiode to generate the electrical signal used to change the deflection profile of the MEMS mirror.

5. *(original)* The arrangement as defined in claim 1 wherein the active light source comprises a laser.

6. *(original)* The arrangement as defined in claim 1 wherein the passive receiver of light comprises an optical fiber.

7. - 13. *cancelled*

14. *(previously presented)* An arrangement for continuously controlling the amount of light propagating through a single passive optical receiver, the arrangement comprising

- a passive optical device for propagating optical signals in both a transmitting and a receiving direction;

- an active light source;

- an alignment monitoring photodiode;

- a first and a second MEMS mirror, said first MEMS mirror for reflecting a beam of light from said active light source to said passive device and said second MEMS mirror for reflecting a beam of light from said passive optical device to said monitoring photodiode; and

- a control circuit disposed between the alignment monitoring photodiode and said first and second MEMS mirrors, said control circuit responding to changes in optical power received by said alignment monitoring photodiode and generating alignment correction signals to said first and second MEMS mirrors to modify the deflection profile of said first and second MEMS mirrors and provide optical realignment between the passive optical device and the active light source.